

Atty. Dkt. No. AMAT/4714.C1/CPI/WCVD/PJS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Xi, et al.

Serial No.: 10/762,764

Confirmation No.: 3117

Filed: January 22, 2004

For: Method and Apparatus for  
Depositing Refractory Metal  
Layers Employing Sequential  
Deposition Techniques to Form a  
Nucleation Layer

Group Art Unit: 2829

**Examiner:** David A. Zarneke

**MAIL STOP AMENDMENT**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

Dear Sir:

**CERTIFICATE OF MAILING**  
**37 CFR 1.8**

I hereby certify that this correspondence is being deposited on 12/24, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

12/21/04                      Kristen E. Rhee  
Date                                      Signature

**RESPONSE TO OFFICE ACTION DATED OCTOBER 7, 2004**

In response to the Office Action dated October 7, 2004, having a shortened statutory period for response set to expire on January 7, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. Authorization to charge the sum of \$650.00 for 13 additional claims in excess of twenty is given in a separate fee transmittal.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.

12/29/2004 RMEBRAHT 00000002 501074 10762764

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